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1762

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TRANSMITTAL FORM (to be used for all correspondence after initial filing)	Application Number	09/905,718
	Filing Date	May 16, 2002
	First Named Inventor	Willson, Carlton G. et al.
	Art Unit	1762
	Examiner Name	Bernard D. Pianalto
Total Number of Pages in This Submission	Attorney Docket Number	PA27/UTS-26-03Q12

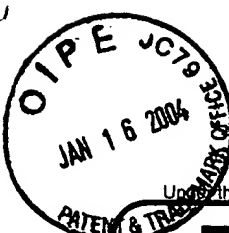
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FEE TRANSMITTAL for FY 2004

Effective 10/01/2003. Patent fees are subject to annual revision.

☐ Applicant claims small entity status. See 37 CFR 1.27

TOTAL AMOUNT OF PAYMENT (\$) 600.00

Complete if Known

Application Number	09/905,718
Filing Date	May 16, 2002
First Named Inventor	Willson, Carlton G.
Examiner Name	1762
Art Unit	Bernard D. Pianalto
Attorney Docket No.	PA27/UTS-26-03Q12

METHOD OF PAYMENT (check all that apply)

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FEE CALCULATION

1. BASIC FILING FEE

Large Entity	Small Entity	Fee Description	Fee Paid
Fee Code (\$)	Fee Code (\$)		
1001 770	2001 385	Utility filing fee	
1002 340	2002 170	Design filing fee	
1003 530	2003 265	Plant filing fee	
1004 770	2004 385	Reissue filing fee	
1005 160	2005 80	Provisional filing fee	
SUBTOTAL (1)			(\$) 0.00

2. EXTRA CLAIM FEES FOR UTILITY AND REISSUE

Total Claims: -20** = X =
Independent Claims: -3** = X =
Multiple Dependent: =

Large Entity	Small Entity	Fee Description	Fee Paid
Fee Code (\$)	Fee Code (\$)		
1202 18	2202 9	Claims in excess of 20	
1201 86	2201 43	Independent claims in excess of 3	
1203 290	2203 145	Multiple dependent claim, if not paid	
1204 86	2204 43	** Reissue independent claims over original patent	
1205 18	2205 9	** Reissue claims in excess of 20 and over original patent	
SUBTOTAL (2)			(\$) 0.00

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FEE CALCULATION (continued)

3. ADDITIONAL FEES

Large Entity	Small Entity	Fee Description	Fee Paid
Fee Code (\$)	Fee Code (\$)		
1051 130	2051 65	Surcharge - late filing fee or oath	
1052 50	2052 25	Surcharge - late provisional filing fee or cover sheet	
1053 130	1053 130	Non-English specification	
1812 2,520	1812 2,520	For filing a request for ex parte reexamination	
1804 920*	1804 920*	Requesting publication of SIR prior to Examiner action	
1805 1,840*	1805 1,840*	Requesting publication of SIR after Examiner action	
1251 110	2251 55	Extension for reply within first month	
1252 420	2252 210	Extension for reply within second month	420.00
1253 950	2253 475	Extension for reply within third month	
1254 1,480	2254 740	Extension for reply within fourth month	
1255 2,010	2255 1,005	Extension for reply within fifth month	
1401 330	2401 165	Notice of Appeal	
1402 330	2402 165	Filing a brief in support of an appeal	
1403 290	2403 145	Request for oral hearing	
1451 1,510	1451 1,510	Petition to institute a public use proceeding	
1452 110	2452 55	Petition to revive - unavoidable	
1453 1,330	2453 665	Petition to revive - unintentional	
1501 1,330	2501 665	Utility issue fee (or reissue)	
1502 480	2502 240	Design issue fee	
1503 640	2503 320	Plant issue fee	
1460 130	1460 130	Petitions to the Commissioner	
1807 50	1807 50	Processing fee under 37 CFR 1.17(q)	
1806 180	1806 180	Submission of Information Disclosure Stmt	180.00
8021 40	8021 40	Recording each patent assignment per property (times number of properties)	
1809 770	2809 385	Filing a submission after final rejection (37 CFR 1.129(a))	
1810 770	2810 385	For each additional invention to be examined (37 CFR 1.129(b))	
1801 770	2801 385	Request for Continued Examination (RCE)	
1802 900	1802 900	Request for expedited examination of a design application	
Other fee (specify)			
*Reduced by Basic Filing Fee Paid			
SUBTOTAL (3)			(\$) 600.00

SUBMITTED BY		(Complete (if applicable))	
Name (Print/Type)	Kenneth C. Brooks	Registration No. (Attorney/Agent)	38393
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		Date	January 8, 2004

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Watts et al. PATENT APPLICATION
Serial No.: 09/905,718 Group Art Unit: 1762
Filing Date: May 16, 2002 Examiner: Bernard D. Pianalto
For: METHOD AND SYSTEM FOR FABRICATING NANOSCALE PATTERNS
IN LIGHT CURABLE COMPOSITIONS USING AN ELECTRIC FIELD

INFORMATION DISCLOSURE STATEMENT

Commissioner
for Patents
Alexandria, VA 22313

Sir:

The following information is submitted in compliance with Applicants' duty of disclosure under 37 C.F.R. § 1.56.

Form PTO-1449 and a copy of each reference recited below accompanies this document. It is respectfully requested that the cited information be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

ISSUED PATENTS

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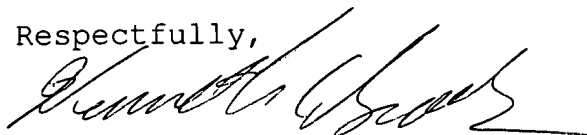
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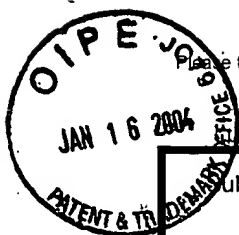
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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

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Complete if Known

Application Number	09/905,718
Filing Date	May 16, 2002
First Named Inventor	Watts et al.
Group Art Unit	1762
Examiner Name	Bernard D. Pianalto
Attorney Docket Number	PA27/UTS-26-03q12

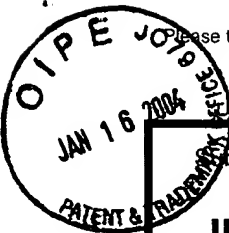
U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
	A1	3,807,027		Heisler	04-30-1974	
	A2	3,807,029		Troeger	04-30-1974	
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			Application Number	09/905,718	
			Filing Date	May 16, 2002	
			First Named Inventor	Watts et al.	
			Group Art Unit	1762	
			Examiner Name	Bernard D. Pianalto	
Sheet	2	of	9	Attorney Docket Number	PA27/UTS-26-03q12

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
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	A36	5,723,176		Keyworth et al.	03-03-1998	
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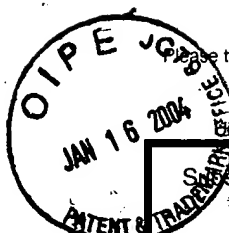
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				Filing Date	May 16, 2002
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				Examiner Name	Bernard D. Pianalto
				Attorney Docket Number	PA27/UTS-26-03q12
Sheet	4	of	9		

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Sheet **5** of **9**

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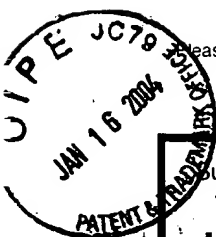
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Sheet 6 of 9

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Application Number	09/905,718
Filing Date	May 16, 2002
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Group Art Unit	1762
Examiner Name	Bernard D. Pianalto
Attorney Docket Number	PA27/UTS-26-03q12

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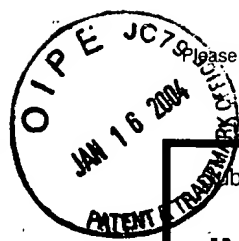
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Sheet	7	of	9	Attorney Docket Number	PA27/UTS-26-03q12

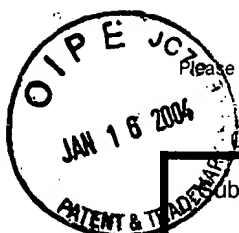
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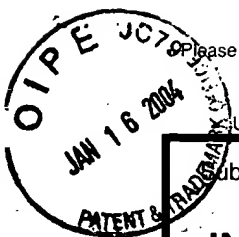
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				Filing Date	May 16, 2002
				First Named Inventor	Watts et al.
				Group Art Unit	1762
				Examiner Name	Bernard D. Pianalto
Sheet	9	of	9	Attorney Docket Number	PA27/UTS-26-03q12

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	A145	CHOI et al., "High Precision Orientation Alignment and Gap Control Stages for Imprint Lithography Processes," U.S. Patent Application 09/698,317, Filed with USPTO on October 27, 2000.	
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	A153	WATTS et al., "Low Viscosity High Resolution Patterning Material," U.S. Patent Application 10/178,947, Filed with USPTO on June 24, 2002.	

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